

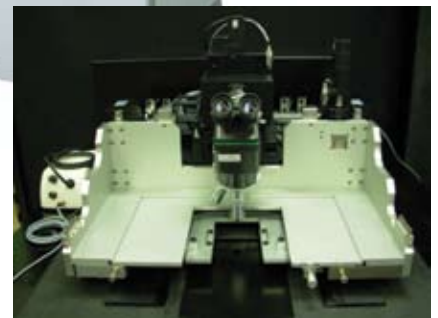
# SEMICAPS SOM 4000

## INVERTED ANALYTICAL AND TESTER-DOCKED SCANNING OPTICAL MICROSCOPE SYSTEM



### Features

- ~ Analytical to tester-docked mode conversion
- ~ 300mm wafer stage with auto-lock feature
- ~ Backside and frontside analysis modes
- ~ Compatible with probe card and manipulators
- ~ High resolution stage with 20nm resolution and 0.5 $\mu$ m repeatability
- ~ High resolution laser scanner with up to 2Kx2K scan resolution
- ~ High power NIR lasers compatible
- ~ Multi-laser induced techniques system
- ~ Multi-detector capability: Si-CCD, InGaAs and InSb
- ~ Refractive and diffractive Solid Immersion Lens (SIL) option
- ~ Thermal management option
- ~ CAD interface option
- ~ Laser marker option



300mm Probe Station



Conversion